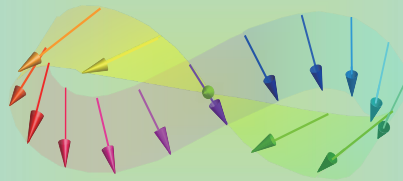


Nanoelectronics

01



Atsufumi Hirohata

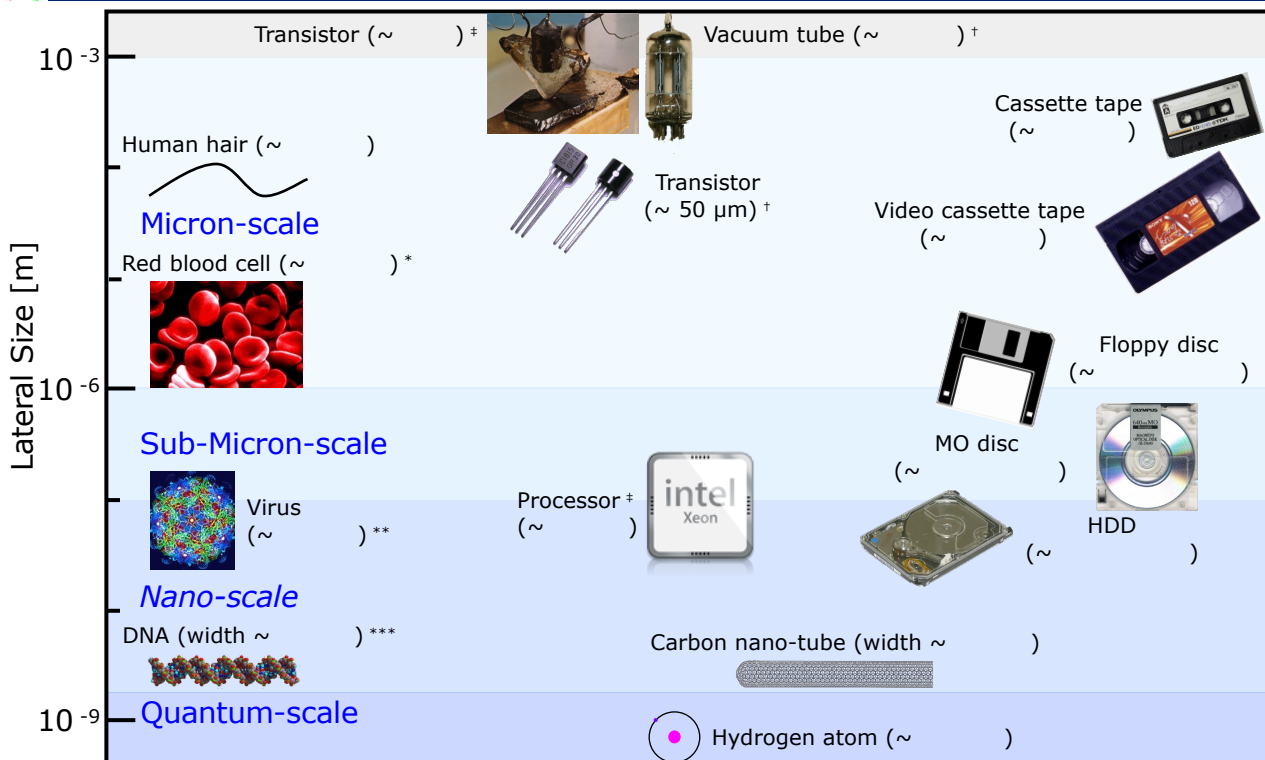
Department of Electronic Engineering

THE UNIVERSITY of York



09:00 Thursday, 19/January/2023 (ENV 005)

Go into Nano-Scale



* http://www.esa.int/esaKIDSen/SEMOC68LURE_LifeinSpace_1.html

** <http://www.guardian.co.uk/pictures/image/0,8543,-11404142447,00.html>

*** <http://www.wired.com/medtech/health/news/2003/02/57674>

† <http://www.wikipedia.org/>

‡ S. M. Sze, *Physics of Semiconductor Devices* (John Wiley, New York, 1981).



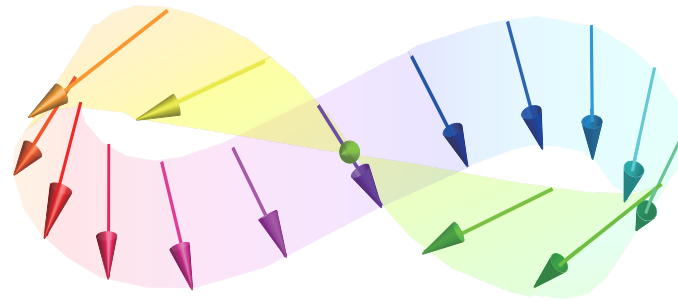
Nanoelectronics

Electronics

- Electron transport
- Magnetism

Material Sciences

- Semiconductors
- Ferromagnets
- Superconductors
- Organic materials



Physics

- Electromagnetism
- Quantum mechanics



Contents of Nanoelectronics

Lectures : Atsufumi Hirohata (atsufumi.hirohata@york.ac.uk, P/Z 019)

Electrical transport in nanometric scale (Weeks 2 ~ 10)

All lectures will be uploaded weekly in advance at

<http://www-users.york.ac.uk/~ah566/lectures/lectures.html> & [Wiki](#)

09:00 ~ 10:00 Mons. (P/T 005A)

12:00 ~ 13:00 Weds. (P/T 005A)

I. Introduction to nanoelectronics (01)

II. Electromagnetism (02 & 03)

III. Basics of quantum mechanics (04 ~ 06)

IV. Application of quantum mechanics (07, 10, 11, 13 & 14)

V. Nanodevices (08, 09, 12, 15 ~ 18)

Workshops : (1/2 towards the final mark)

Equation solving in quantum physics (Weeks 2, 4, 6 & 8)

All workshop questions will be uploaded weekly in advance at

<http://www-users.york.ac.uk/~ah566/lectures/lectures.html> & [VLE](#)

15:00 ~ 16:00 Fris. (LFA 204X)

Submit your answers via VLE by 12:00 on Thus. On Weeks 4, 6, 8 & 9.

Examination : (1/2 towards the final mark)

Online exam (Equation solving + Essay)



References

General textbooks in nanoelectronics :

K. Goser, P. Glosekotter and J. Diestuhl, *Nanoelectronics and Nanosystems* (Springer, Berlin, 2004); which covers all the topics in the field.

V. V. Mitin, V. A. Kochelap and M. A. Stroscio, *Introduction to Nanoelectronics* (Cambridge University Press, Cambridge, 2008); which focuses on semiconductor nanoelectronics and nanodevices.

Douglas Natelson, *Nanostructures and Nanotechnology* (Cambridge University Press, Cambridge, 2016); which focuses on nanoelectronic devices.

General textbooks in quantum mechanics :

D. J. Griffiths, *Introduction to Quantum Mechanics* (Cambridge University Press, Cambridge, 2017); which covers all the topics in the field.

G. L. Squires, *Problems in Quantum Mechanics* (Cambridge University Press, Cambridge, 1995); which provides broad problems with solutions.

A. Berera and L. Del Debbio, *Quantum Mechanics* (Cambridge University Press, Cambridge, 2022); which provides selected problems with solutions.

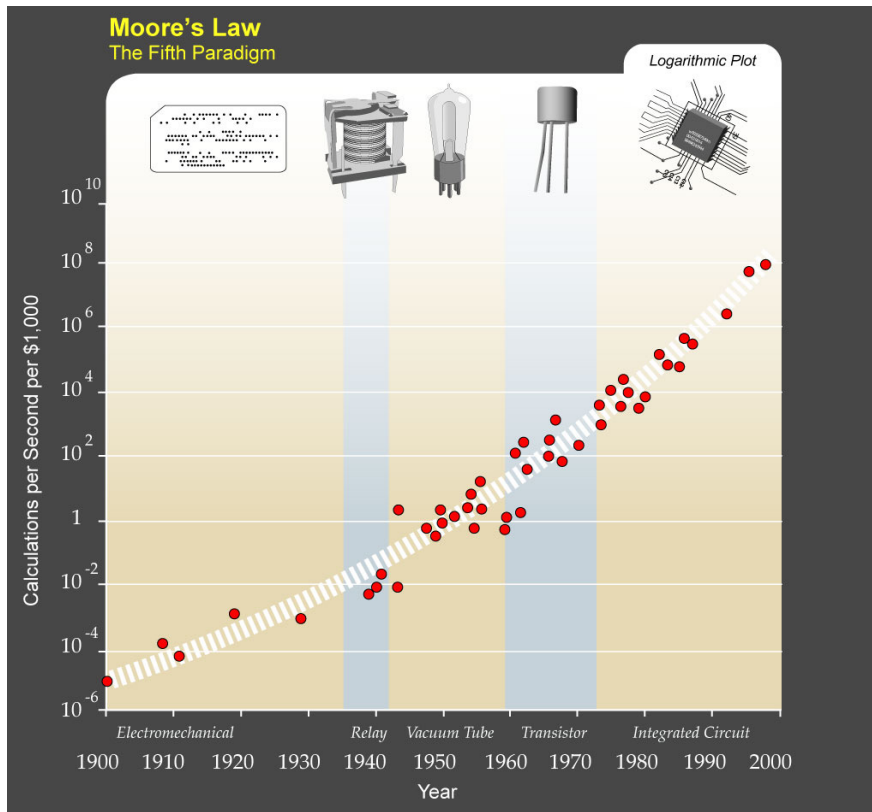
Lecture notes / slides : <http://www-users.york.ac.uk/~ah566/lectures/lectures.html>
& [Wiki](#)

01 Micro- to Nano-Electronics ?

- Device miniaturisation
 - Micron / nanometre
 - Nanofabrication
 - New functionality
 - Electron transport



Miniaturisation of Data Processors



* <http://www.wikipedia.org/>

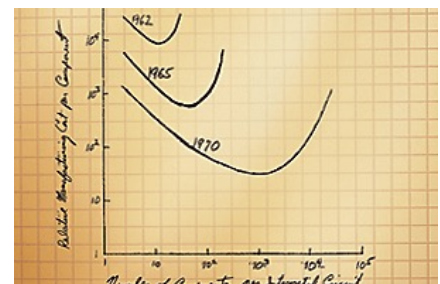
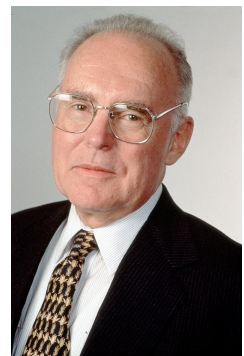
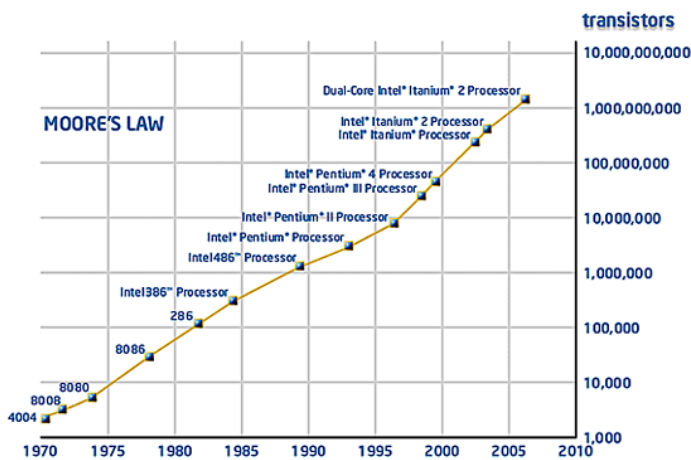


Miniaturisation and Integration in Semiconductor Devices

Moore's law :

“The number of transistors on a chip will double every 18 months.” (1965)

10 years later he revised this to “every 12 months.”



→ The development speed becomes even faster !

* <http://www.intel.com/>

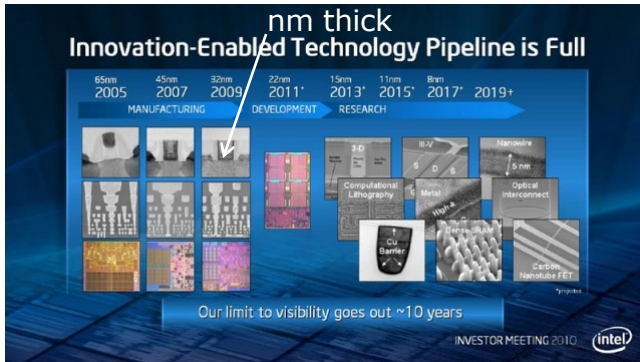
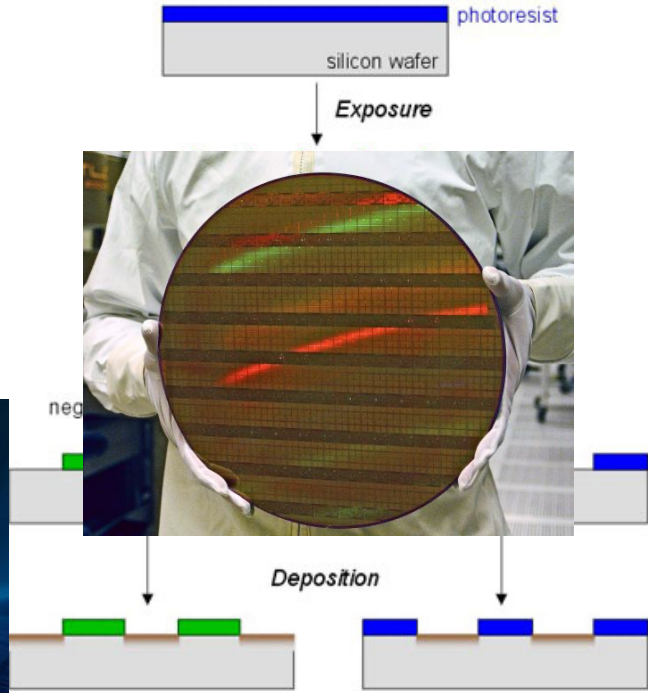


Current Semiconductor Technology

45-nm rule :



Nanofabrication method :



* <http://www.intel.com/>
 ** <http://www.kodak.com/>



Roadmap for Si-Based Devices

Table 1.1 A roadmap for Si-based microelectronics (predictions of the Semiconductor Industry Association)

	1995	1998	2001	2004	2007	2010
Memories, DRAM						
Bits per chip	64 M	256 M	1 G	4 G	16 G	64 G
Cost per bit (milli-cent)	0.017	0.007	0.003	0.001	0.0005	0.0002
Cost per chip (US\$)	11	18	30	40	80	130
Logic, microprocessors						
Transistors per cm ²	4 M	7 M	13 M	25 M	50 M	90 M
Cost per transistor (milli-cent)	1	0.5	0.2	0.1	0.05	0.02
Power supply (V)	3.3	2.5	1.8	1.5	1.2	0.9
Parameters						
Minimum feature size (μm)	0.35	0.25	0.18	0.13	0.10	0.07
Wafer size (in.)	8	8	12	12	16	16
Electrical defect density per m ²	240	160	140	120	100	25

The data are from U. König, *Physica Scripta*, T68, 90, 1996.

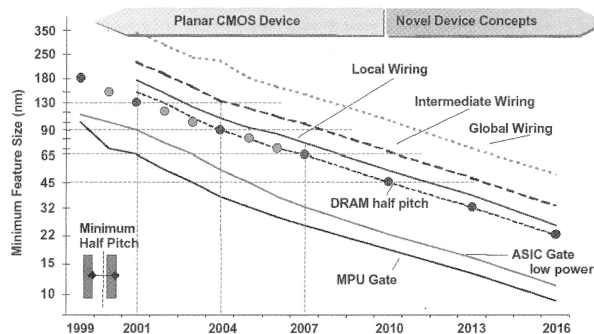
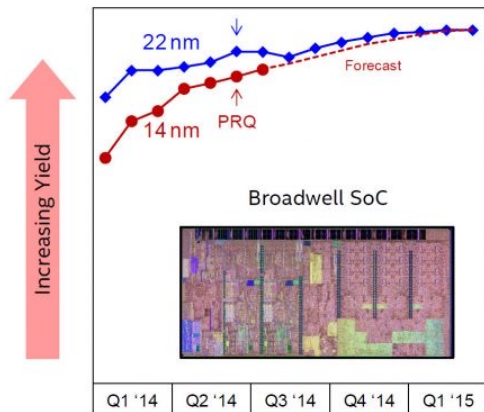


Figure 1.1 Technology nodes and minimum feature sizes from application ITRS Roadmap: MPU, Micro Processing Unit; ASIC, Application-Specific Integrated Circuit. Used with permission, from W. Klingenstein (2002). *Technology Roadmap for Semiconductors*. http://broadband02.ici.ro/program/klingenstein_3d.pdf, page 15. © Infineon Technologies AG, 2002.

* V. V. Mitin, V. A. Kochelap and M. A. Strosio, *Introduction to Nanoelectronics* (Cambridge University Press, Cambridge, 2008).



14 nm Broadwell SoC Yield Trend



22 nm data are shifted to align date of lead product qual
 Depicts relative health, lines not to scale

- 14 nm product yield is now in healthy range with further improvements coming
- Process and lead product are qualified and in volume production
- 14 nm manufacturing fabs are located in Oregon (2014), Arizona (2014) and Ireland (2015)
- Production yield and wafer volume are projected to meet the needs of multiple 14 nm product ramps in 1H '15

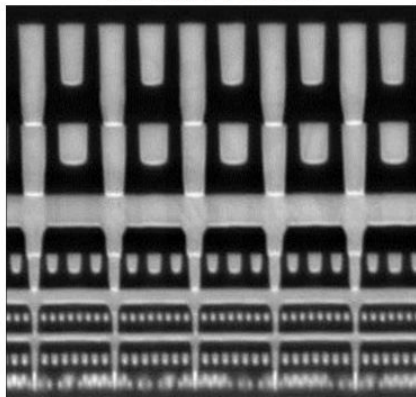
Leadership Technologies are Never Easy (at First!)



Cross-Section of Latest Chips

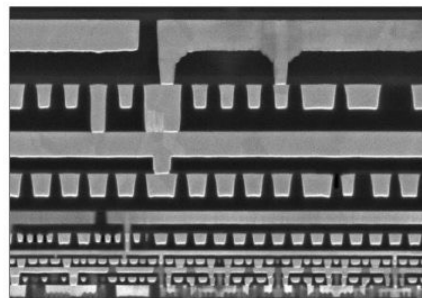
Interconnects

22 nm Process



80 nm minimum pitch

14 nm Process



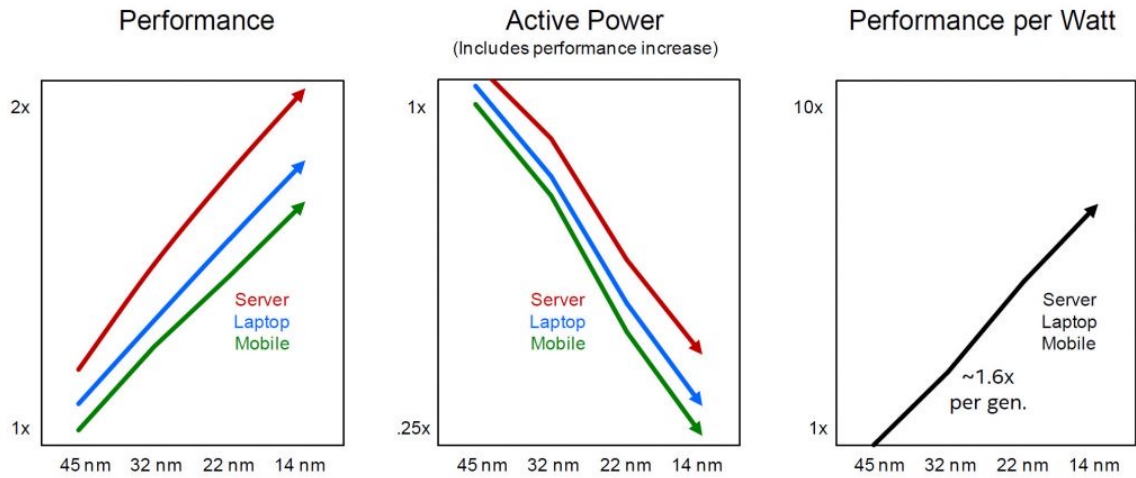
52 nm (0.65x) minimum pitch

52 nm Interconnect Pitch Provides Better-than-normal Interconnect Scaling



Advantages of Latest Chips

Product Benefits



New technology generations provide improved performance and/or reduced power, but the key benefit is improved performance per watt

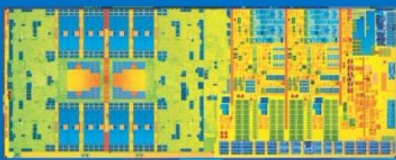


Improvements by Latest Chips

5th Gen Intel Core Processor Generational Improvements

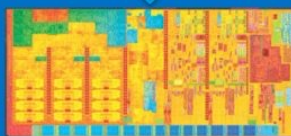
Intel® Core™ i7-5600U Processor with Intel® HD Graphics 5500 compared to 4th Generation Intel® Core™ i7-4600U with Intel® HD Graphics 4400¹

4th Gen Intel® Core™ Processor
0.96B transistors, 131mm²



35% more transistors

37% smaller die size



5th Gen Intel® Core™ Processor
1.3B transistors, 82mm²



3D GRAPHICS

Up to **22%** BETTER



VIDEO CONVERSION

Up to **50%** FASTER



PRODUCTIVITY

Up to **4%** BETTER



BATTERY LIFE

Up to **1.5Hr** LONGER

Source: Intel. Productivity: SYSmark, 2014. 3D Graphics: 3DMark, IceStorm, Unlimited v1.2, Video Conversion: Cyberlink® MediaEspresso™ to convert HD videos. Battery Life based on 40Whr battery capacity watching local 1080p movie. Software and workloads used in performance tests may have been optimized for performance only on Intel microprocessors. Performance tests, such as SYSmark and MobileMark, are measured using specific computer systems, configurations, and workloads. Results may vary. Intel is not responsible for any errors or omissions in this document. Intel reserves the right to change specifications without notice. For more information go to <http://www.intel.com/performance>

¹Configuration detail in Appendix A

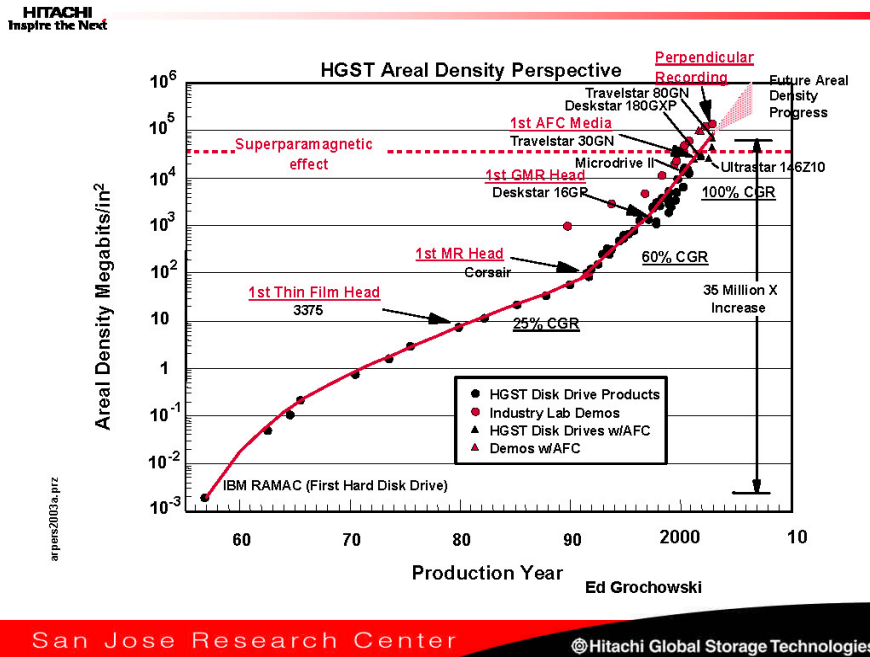


Increase in Recording Density of Hard Disc Drives

Similar to Moore's law :

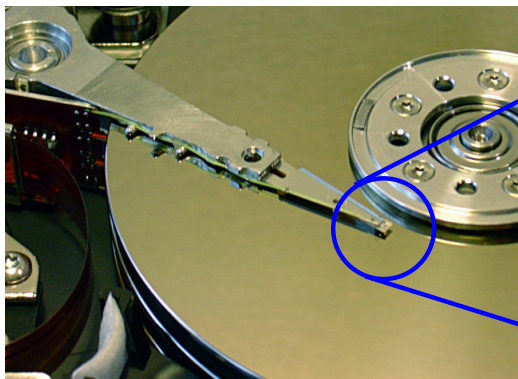
Areal density in a hard disc drive (HDD) will double every 12 months. (~ 1992)

After giant magnetoresistance (GMR) implementation, it will double less than every 12 months. (1992 ~)



How Does a Recording Head Look Like ?

Recording media ...

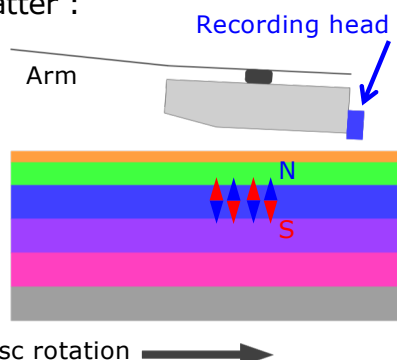


Recording head ...



Configurations of a platter :

- Lubricant ~ 1 nm
- Carbon coating < 15 nm
- Magnetic media ~ 30 nm
- Chromium buffer ~ 50 nm
- Nickel buffer ~ 10 Mm
- Metallic/glass substrate



If the head is a jumbo jet (B747)...



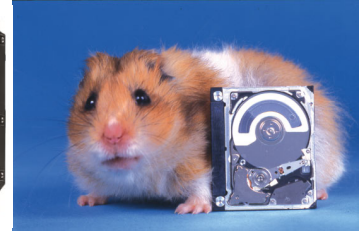


Development of HDD

Recording density increases at $\sim 100\%$ / year :



First HDD in the world :
 RAMMAC 305 (1956, IBM)
 cm (in) platter $\times 50 = 4.4$ MB
 Mbit / in² 920 kg
 \$ / GB



Current HDD :
 Ultrastar DC HC650 (2020, WD)
 cm (in) platter $\times 9 = 20$ TB
 Tbit / in² 690 g
 \$ 0.03 / GB

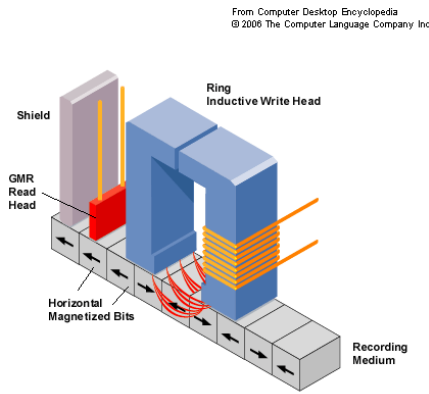
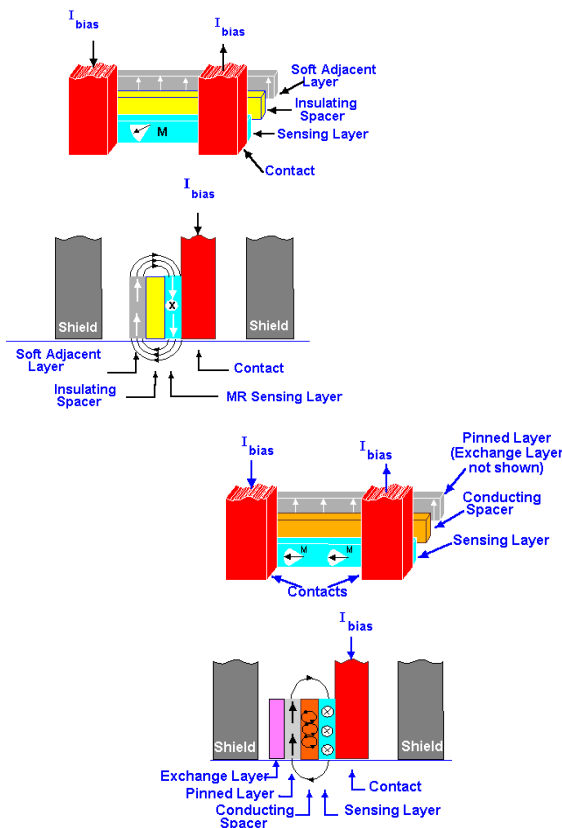
What can you get from such development ?



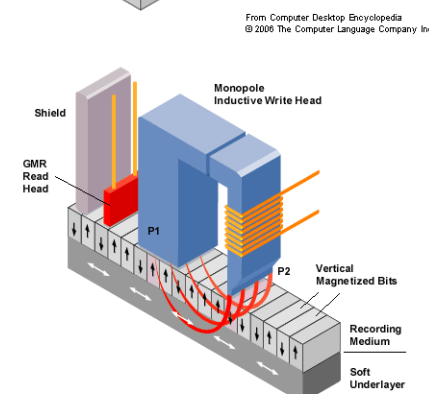
Current Magnetic Recording Technology

Anisotropic to Giant magnetoresistance :

Longitudinal to perpendicular recording :



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From Computer Desktop Encyclopedia © 2008 The Computer Language Company Inc.

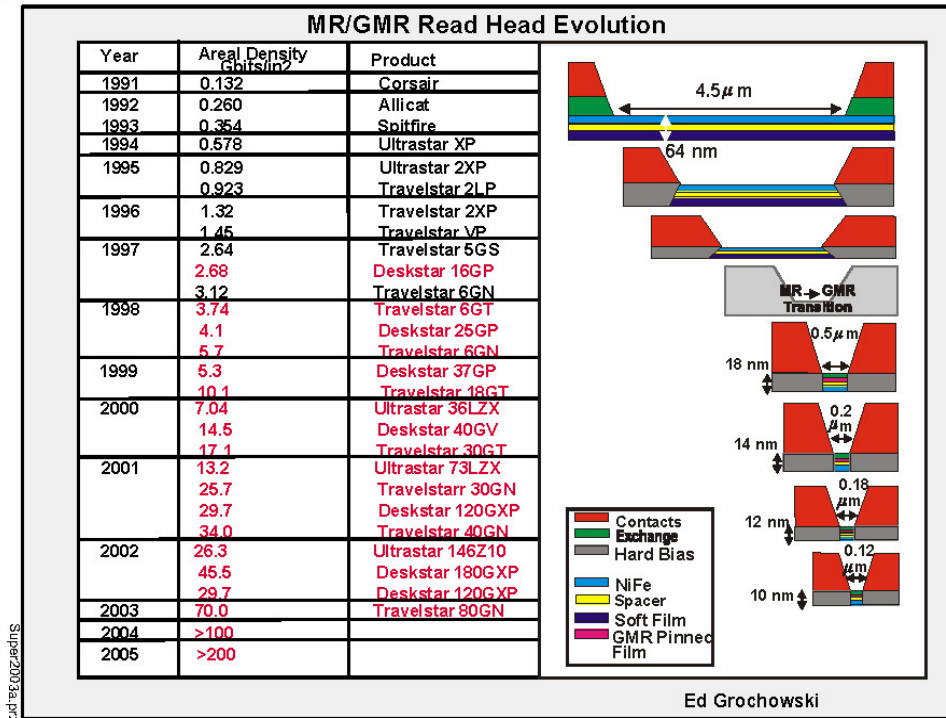
* <http://www.hitachigst.com/>



Miniaturisation in Magnetic Recording Technology

Size evolution of a recording head in a HDD :

HITACHI
Inspire the Next

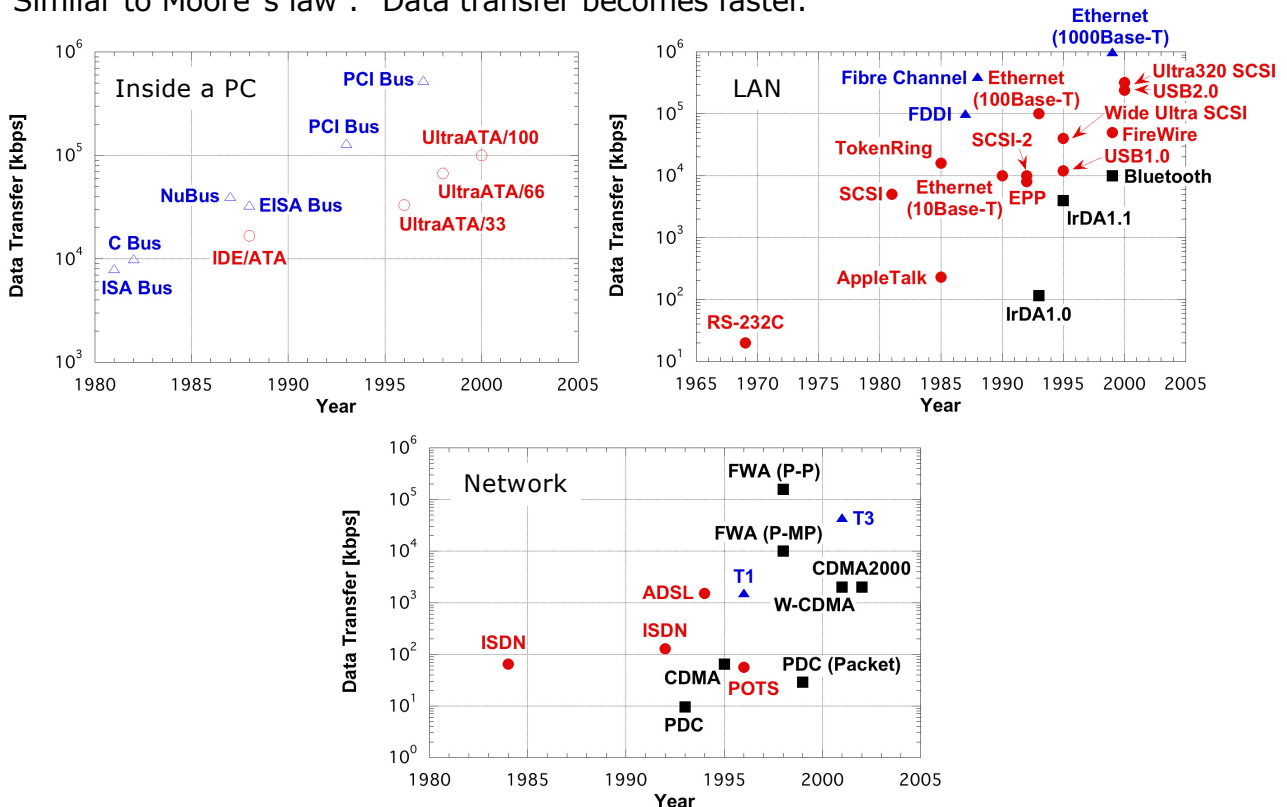


San Jose Research Center Hitachi Global Storage Technologies



Advancement in Communication Technologies

Similar to Moore's law : Data transfer becomes faster.





Advantages of Nano-Scale Miniaturisation

From microelectronics to nanoelectronics :

- ✓ Reduction of effective electron paths
 - ✓ Reduction of electron scattering
- Faster operation

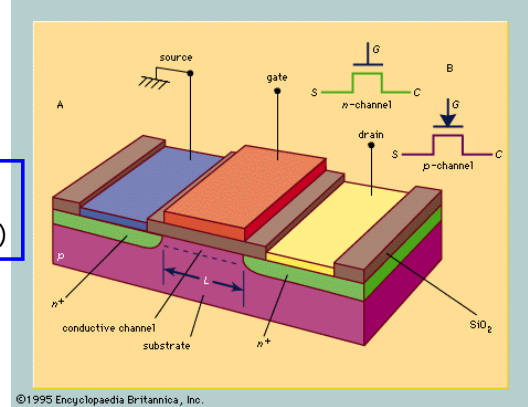
- ✗ More complicated fabrication processes
- ✗ Higher fabrication cost
- ✗ Larger distributions in device properties

- ✗ Leakage currents (insulator < 1nm thick)
- ✗ No electron confinement (path < 10 nm thick)

- ✗ Joule heating

→ Need to be solved in *Nanoelectronics*

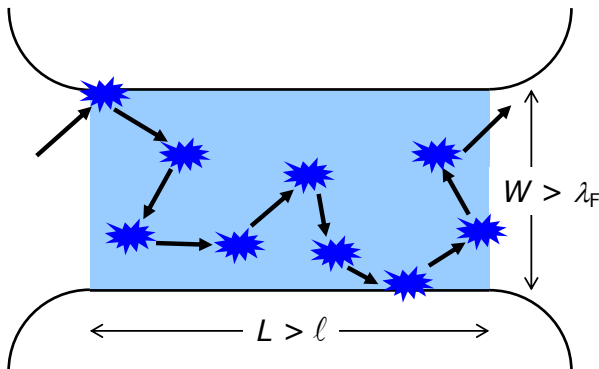
- *Electromagnetism*
- *Quantum physics*
- *Nano-device fabrication*



Electron Transport in a Nano-Device

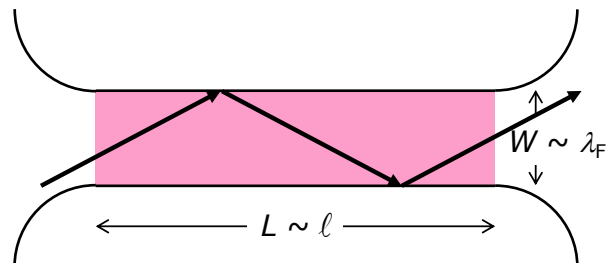
transport :

Electron scattering
→ Electrical resistivity



transport :

Negligible electron scattering
→ Negligible electrical resistivity
≈ Transport in a vacuum



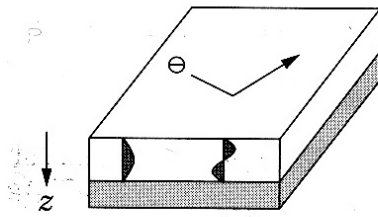
l : electron mean free path (\sim nm for Cu @ RT)
 λ_F : Fermi wave length (\sim nm)

Hot-electron

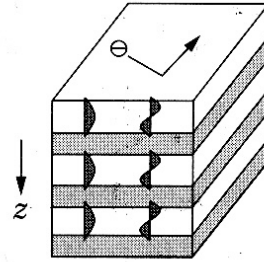


Electron Transport in Nano-Structures

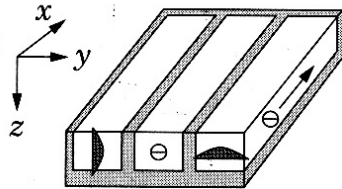
4 fundamental nano-device structures :



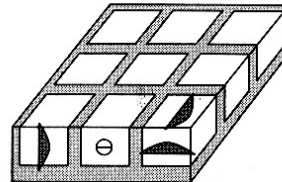
Ultrathin film (quantum well)



Superlattice (multilayer)



Quantum wire (nano-wire)



Quantum dot (nano-dot)

* H. Sakaki and N. Yokoyama, *Nanoelectronics* (Ohm-sha, Tokyo, 2004).